

EVG announces multi-functional micro- and nanoimprint solution 'EVG 7300' - January 20, 2022

EVG introduced the EVG®7300 automated SmartNIL® nanoimprint and wafer-level optics system. This industry-ready, multi-functional system is designed to serve advanced R&D and production needs for a wide range of emerging applications involving micro- and nano-patterning as well as functional layer stacking. The EVG7300 system is offered as both a stand-alone tool as well as an integrated module in EVG's HERCULES® NIL fully integrated UV-NIL track solution where additional pre-processing steps, such as cleaning, resist coating and baking or post-processing, can be added to optimize for particular process needs.



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